



ZFW

PATENT  
Attorney Docket No. 04329.3147

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	) Group Art Unit: 1756
	)
Kyoko Izuha et al.	)
	) Examiner: Rosasco, Stephen D.
Application No.: 10/668,245	)
	) Notice of Allowance Dated: March 28, 2006
Filed: September 24, 2003	)
	) <b>Mail Stop Issue Fee</b>
For: MASK, MANUFACTURING	)
METHOD FOR MASK, AND	) Confirmation No.: 2059
MANUFACTURING METHOD	
FOR SEMICONDUCTOR	
DEVICE	

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT AFTER ALLOWANCE**

Pursuant to 37 C.F.R. § 1.312 and subject to the recommendation of the Examiner and the approval of the Director, and without withdrawing the case from issue, kindly amend the subject application as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks/Arguments** follow the amendment sections of this paper.